

Effective from Session:							
Course Code	EC501	Title of the Course	Semiconductor Device Modeling & Circuit Simulation	L	Т	Р	С
Year	Ι	Semester	Ι	3	1	0	4
Pre-Requisite	VLSI Design	Co-requisite					
Course Objectives	 Several Semico effects . 	classes of semico onductor devices,	g principles of electronic circuits. nductor devices will be covered in this subject BJT and its second order effects, FET and its ent circuits simulation will also be given.		ond or	der	

	Course Outcomes
CO1	Student will be able to understand the Compound semiconductors
CO2	Students will be able to understand and analyze the basics of semiconductor devices and their second order effects
CO3	For a given Model, Students will be able to understand about the models, analyze and examine the various models
CO4	Students will be able to understand second order effects of second order effects
CO5	Students will be able to understand various types of circuits models for MOSFET

Unit No.	Title of the Unit	Content of Unit	Contact Hrs.	Mapped CO						
1	Compound semiconductors	Compound semiconductors, Lattice structures, Carrier drift, Direct and indirect semiconductors Scattering, Recombination, Mean life time, Continuity equation	8	1						
2	PN junction, BJT characteristics	PN junction characteristics, Current components in diode, Equivalent circuits of diode, BJT characteristics, Second order effects in BJT: Thermal runaway, Base width modulation, Kirk effect, Band gap narrowing, Small signal analysis.	8	2						
3	Models	Eber's moll model, Hybrid pi model, Figure of merit, approximate model and complete equivalent model of BJT, Charge control model, Gummel poon model, SPICE model of BJT, Simulation of BJT	8	3						
4	Second Order Effects of MOS	N-channel, P-channel MOS characteristics and features, Enhancement and depletion mode: second order effects of MOS: Body effect, Channel length modulation, Subthreshold conduction, DIBL, Hot carrier effect, Mobility degradation, Velocity saturation, CMOS latch up, MOS parasitic capacitances and resistances.	8	4						
5	Circuits models for MOSFET	Circuits models for MOSFET: small signal, SPICE models, BSIM model, Simulation and Layout design DC, AC and Transient analysis of linear and nonlinear circuits, logic and timing simulations.	8	5						
Referen	ce Books:									
	1. Baker, Li, Boyce "CMOS Layout, Design and simulation", PHI 4. Sze S.M. " Semiconductor Physics" MacGraw Hill publication									
2. Ra	*									
3. Ka										
4. Mi	illman, Halkias " El	ectronic Devices and Circuits" TMH publication								

e-Learning Source:

5. https://onlinecourses.nptel.ac.in/noc21_ee80/preview

6. https://digimat.in/nptel/courses/video/117106033/L35.html

						C	ourse A	Articul	ation N	Aatrix:	(Mappii	ng of COs	s with PO	s and PSC	Ds)			
PO- PSO	PO1	PO2	PO3	PO4	PO5	PO6	PO7	PO8	PO9	PO10	PO11	PO12	PSO1	PSO2	PSO3	PSO4	PSO5	PSO6
CO																		
CO1	3	2										2	1					
CO2	3	2											2		2			
CO3	3	2	3										1	2		2		

CO4	3	3	3	3										1	1	3	
CO5	3					3		1				2	2	2	1		
					1- I	Low C	orrelat	ion; 2-	Mode	rate Co	rrelatio	1; 3- Subs	stantial C	orrelatior	1		

Name	&	Sign	of	Program	Coordinator
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Effective from Session:							
Course Code	EC502	Title of the Course	VLSI Devices & Circuits	L	Т	Р	С
Year	Ι	Semester	Ι	3	1	0	4
Pre-Requisite	SC Devices and IC Technology	Co-requisite					
Course Objectives	 To understand the underlying To learn the analysis of a MC To learn how the parasites improvement techniques. To learn the design methodol 	OS circuits and system arise and affect the	ns and encoding of VLSI systems perfo				

	Course Outcomes
CO1	Given a system Students shall be able to understand properties of digital systems, regenerative property, NMOS, PMOS, pull up and pull-down networks, NAND/NOR, EX-OR, Decoder and short channel effects.
CO2	For a given system, student shall be able to analyze standard CMOS circuits, Pseudo NMOS, Pass Transistor Logic (PTL), Transmission gate Adder/ Subtractor, Design of Combinational circuits and Sizing of MOSFETs.
CO3	For a given Sequential Circuit system students can understand Latches & Flip-flops and Dynamic CMOS and Domino CMOS.
CO4	Students shall be able to identify the technology for Standard cells, Circuit implementation using PAL and PLA, FPGA, Look up tables (LUTs).
CO5	For a given a system, able to design RAM, ROM, basic cells of SRAM and DRAM, GaAs MESFET and Bi-CMOS: features, inverter, conventional and full swing BiCMOS circuits.

Unit No.	Title of the Unit	Content of Unit	Contact Hrs.	Mapped CO
1	Digital System	Properties of digital systems, regenerative property, NMOS, PMOS, pull up and pull-down networks, strong 1 and strong 0, NAND/NOR, EX-OR, Decoder, MUX, Micron and Sub-micron devices: Scaling, Short channel effects	8	1
2	CMOS Circuits	Standard CMOS circuits, Pseudo NMOS, Pass Transistor Logic (PTL), types of PTL, advantages and disadvantages of PTL, Level restorer, Transmission gate Adder/ Subtractor, Design of Combinational circuits and Sizing of MOSFETs	8	2
3	Sequential Circuits	Dynamic CMOS and Domino CMOS, Complex gates, Sequential Circuits: Latches & Flip-flops, Problems of race, race around and 1's catching	8	3
4	PLDs	Standard cells, Circuit implementation using PAL and PLA, FPGA, Look up tables (LUTs), Importance of FPGA	8	4
5	Memories	RAM, ROM, basic cells of SRAM and DRAM, 6T RAM, 3T RAM, 1T RAM, GaAs MESFET, its characteristics and applications, Bi-CMOS: features, inverter, conventional and full swing BiCMOS circuits.	8	5
Referen	ce Books:			
•	Rabaey Jan M, Cha	ndrakasan Anantha, Nikolic Borivoje "Digital Integrated Circuits" PHI publication.		
•	Hodges, Jackson, Sa	aleh "Analysis and Design of Digital Integrated Circuits" McGraw Hill publication.		
•	Kang Sung-Mo, Lel	blebici Yusuf "CMOS Digital Integrated Circuits" Tata McGraw Hill publication.		
•	Rabaey Jan M, Cha	ndrakasan Anantha, Nikolic Borivoje "Digital Integrated Circuits" PHI publication.		
•	Hodges, Jackson, Sa	aleh "Analysis and Design of Digital Integrated Circuits" McGraw Hill publication.		
•	Sedra ,Smith " Micr	oelectronic Circuits" Oxford Publication		
•	Islam S.S "Semicon	ductor Devices and Physics" Oxford Publication		
e-Lear	rning Source:			
	//www.slideshare.net/ 41704d1&v=&b=&fr	imrankhan2142/unit-1-traditional-cmos-design?qid=0a8c9b4a-990a-49e0-b30b- om_search=11		

						Cou	irse Ar	ticulat	ion Matr	ix: (Map	ping of	COs witl	n POs an	d PSOs)		
PO- PSO CO	PO1	PO2	PO3	PO4	PO5	PO6	PO7	PO8	PO9	PO10	PO11	PO12	PSO1	PSO2	PSO3	PSO4
CO1	3	2		2	1	1		1	2				3	2	1	1
CO2	3	2	1	2	1	1			2		1		3	2	1	1
CO3	3	3		1	2				1			1	3	2	2	1
CO4	3	1	2	3	2	1			1				2	1	2	1
CO5	3	3	2	2	1	1			1				2	1	2	1

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Effective from Session:							
Course Code	EC503	Title of the Course	Microelectronics Technology	L	Т	Р	C
Year	Ι	Semester	Ι	3	1	0	4
Pre-Requisite	Electronic Devices and Circuits (EC-201)	Co-requisite					
Course Objectives	 Introduction to different type techniques, cleaning of wafer To understand different types oxide furnaces. To understa furnaces. To learn about different phot To learn about different ion profiles. Introduction of chem To study about different fall technology. To know about 	rs, crystal orientation s of oxidation techniq nd the dopant diffus olithography and mas implantation techniq nical vapor deposition prication steps of IC	and different epitaxial proce ues, thickness measurement sion processes its models a k making and pattern transf ues, its equipment, range a h (CVD) and CVD process i such as bipolar IC, MOS	ess. of ox and di er pro nd do n IC f	tide an fferent cess. pant d abrica	d diffe diffus istribution.	rent sion tion

	Course Outcomes
CO1	Students will be able to identify basic structure of BJT, NMOS, CMOS, BiCMOS Devices. Students will know about Crystal
	Growth & Silicon wafer preparation, cleaning and crystal orientation and defects. Students will able to compute different
	vapor phase epitaxial process and redistribution of impurities during epitaxy.
CO2	Students shall able to understand different types of oxidation techniques and different oxide furnaces. Students will able to
	compute the thickness of the oxide. Students will able to understand dielectrics and polysilicon film deposition.
CO3	Student shall be able to select the suitable photolithography. To make mask making learn about pattern transfer process.
CO4	Students will able to understand identify different ion implantation equipment and its process. Students will able to compute
	range and dopant distribution profiles. Develop an understanding about chemical vapor deposition (CVD) and CVD process in
	IC fabrication.
CO5	Student shall be able to explain about fabrication steps of IC such as bipolar IC, MOS IC, and BiCMOS IC technology.
	To know about fault detection and characterization technique.

Unit No.	Title of the Unit	Content of Unit	Contact Hrs.	Mapped CO
1	Introduction, Crystal Growth & Silicon wafer preparation and Epitaxy	 Basic structure of BJT, NMOS, CMOS, BiCMOS Devices. Introduction, Structure of Semiconductor, Electron- Grade Silicon, CZ Crystal Growth, Silicon Shaping, Processing considerations. Introduction, Vapour-Phase Epitaxy, Molecular beam Epitaxy, Silicon on Insulator, Epitaxial Evaluation. 	8	1
2	Oxidation & Dielectrics and Polysilicon Film Deposition	 Introduction, Growth Mechanism and Kinetics, Thin oxidation, Oxidation Technique and System, Oxidation Properties, Redistribution of Dopants at interface, Oxidation of Polysilicon, Oxidation Induced Defects. Introduction, Deposition Process, polysilicon, Silicon Dioxide, Silicon Nitride, Plasma Assisted Deposition. 	8	2
3	Lithography, Etching & Diffusion	 Introduction, Optical Lithography, Electron Lithography, X-ray Lithography, Ion Lithography. Wet and Dry Chemical Etching, Reactive Plasma Etching. Introduction, Model of diffusion, in solid, Diffusivities of B, P, As and Sb, Measurement Techniques. 	8	3
4	Ion Implantation & Metallization	 Introduction, Range Theory (Jon Stopping, Range Distribution, Damages, Channeling), Annealing, Shallow Junction, High Energy Implantation. Chemical Vapour Deposition (CVD), Physical Vapour Deposition (PVD), Evaporation technique, sputtering technique. 	8	4
5	Fabrication steps of IC	• Bipolar IC, MOS IC, BiCMOS IC, Fault Detection and Characterization Technique.	8	5
Referen	ce Books:			
•		SI Technology", Mc Graw Hill International.		
•	Gandhi S, "VLSI fa	brication principles", Wiley Publication.		

- Campbell S A, "The Science and Engineering of Microelectronics fabrication" Oxford University press.
- Geiger Randall L, Allen Phillip E, Stader Noel R, "VLSI Design Technique for Analog and Digital Circuits", Mc Graw Hill International.

e-Learning Source:

https://onlinecourses.nptel.ac.in/noc21_ee86/preview

https://youtu.be/366BVdmcUxk

		Course Articulation Matrix: (Mapping of COs with POs and PSOs)														
PO- PSO CO	PO1	PO2	PO3	PO4	PO5	PO6	PO7	PO8	PO9	PO10	PO11	PO12	PSO1	PSO2	PSO3	PSO4
CO1	3	3	1	2	1	1		1	2				3	2	1	1
CO2	3	1		3	2	1			2		1		3	2	1	1
CO3	3	3		1	2	1			1			1	3	2	2	1
CO4	3	1	2	3	2	1			1				2	1	2	1
CO5	3	3	2	2	1	1			1				2	1	2	1

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Effective from Session:													
Course Code	EC504	Title of the Course	Title of the Course Digital System Design using Verilog HDL L										
Year	1	Semester	1	3	1	0	4						
Pre-Requisite	NA Co-requisite NA												
Course Objectives	 Improve the To explain t To explain t To explain t To Study of Place & Rout 	e student's skills in the l combinational ,sequentia he verilog HDL with de he test bench and simul RTL Coding Guidelin e Tool.	nd basic knowledge in the fields of HDL programming. logical design of digital systems. al circuits and Concept of PLA and PLDs. etailed study of structural data flow and behavioral modeling ation of combinational and sequential circuits es, Modelsim Simulation Tool, Synthesis Tool, Synplify To , Design of Arithmetic Circuits, System Design	-	linx								

	Course Outcomes
CO1	Student will be able to understand the concept of VLSI Design flow and will able design the combinational circuit using PLDs and PAL.
CO2	Student will able design the sequential circuit i.e. different types of registers and counters etc. Student will be able to understand the concept
	of Design Flow of VLSI Circuits
CO3	Student will be able to explain HDL languages and its type .Student will able to design combinational and sequential circuit using structural
	modeling, dataflow modeling and behavioral modeling of Verilog HDL
CO4	Student will able to write the test bench of digital circuits. Student will able to design system using ASM Chart, able to work on Modelsim
	and will able to simulate the combinational and sequential circuit on it.
CO5	Student will able to design the ROM, RAM, arithmetic circuits and system like ATM machine, weighing machine etc. using Verilog HDL.

Unit No.	Title of the Unit	Content of Unit	Contact Hrs.	Mapped CO
1		Introduction to VLSI Design, Combinational Circuit Design, Programmable Logic Devices, Programmable Array Logic.	8	1
2		Review of Flip-Flops, Sequential Circuits, Sequential Circuit Design, Design Flow of VLSI Circuits.	8	2
3		Verilog Modeling of Combinational Circuits, Modeling of Verilog Sequential Circuits, RTL Coding Guidelines, Coding Organization - Complete Realization.	8	3
4		Writing a Test Bench, System Design using ASM Chart, Example of System Design using ASM Chart, Examples of System Design using Sequential Circuits, Simulation of Combinational and Sequential Circuits, Analysis of Waveforms using Modelsim.	8	4
5		Model Sim Simulation Tool, Synthesis Tool, Synplify Tool - Schematic Circuit Diagram View, Xilinx Place & Route Tool, Design of Memories – ROM, RAM, Design of Arithmetic Circuits, System Design Examples.	8	5
Referen	ce Books:			
1. "John	F Wakerley,"Digital D	esign Principles and Practice", PHI		
2. Samir	r Palnitkar, "Verilog HD	L: A Guide to Digital Design and Synthesis", PHI.		
e-Lean	rning Source:			

	Course Articulation Matrix: (Mapping of COs with POs and PSOs)																	
PO- PSO	PO1	PO2	PO3	PO4	PO5	PO6	PO7	PO8	PO9	PO10	PO11	PO12	PSO1	PSO2	PSO4	PSO5	PSO6	PSO7
СО																		
CO1	3	3	3	1					2		1	3	3	3				
CO2	3	3	3	1					2		2	3	2	3				
CO3	3	3	3	3	3		2	2	2		2	3	3	3				
CO4	3	3	3	3	3		2	2	2	2	2	3	3	3				
CO5	3	3	3	3	3	1	3	3	2	2	2	3	1	1				

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Effective from Session: 2022	2-23												
Course Code	EC505	Title of the Course	Device Modeling & Circuits Simulation Lab	L	Т	Р	С						
Year	Ι	Semester	Ι	0	0	2	1						
Pre-Requisite	EC505	EC505 Co-requisite											
Course Objectives	 micron f To learn To under pump i. pump and pump and pump	technology. a basic experimental erstand basic experin- e. Reciprocating ad Gear oil pump.	nental technique to determine impact of NMOS i technique to determine nental technique to determine efficiency of positi ental technique to determine efficiency of hydrau	ve di	splace								

	Course Outcomes
C01	Demonstrate basic experimental technique to determine impact of NMOS inverter.
CO2	Demonstrate basic experimental technique to determine symmetrical & delay CMOS inverter.
CO3	Demonstrate basic experimental technique to two input CMOS NAND Inverter. pump and Gear oil pump.
CO4	Design current mirror for given basic component.
CO5	Determine and design power consumption CMOS and CMOS SCHMITT trigger.

Exper iment No.	Title of the Experiment	Content of Unit	Contact Hrs.	Mapped CO
1	NMOS INVERTER	Design a depletion load NMOS inverter VOL <= 0.3 in 5 micron technology V_{TOD} lvolt V_{TOL} =3volt kpl=40 micron amp/volt ² kpd 10 micron amp/volt ² VDD=5 volt. For the above data simulate vtc for lambda 0.05 gamma 0.4 v also calculate noise margin and inverter threshold Voltage.	2	CO1
2	SYMMETRICAL CMOS INVERTER	Design a symmetrical CMOS inverter for a given data VDD=5 volt VTP=VTN=1volt for 5 micron technology kpl=40 micron amp/volt ² kpd 10 micron amp/volt ² for lambda 0.05 gamma 0.4 v calculate (I) VM for VTC (II) calculate noise margin (III) What is minimum CMOS inverter size (IV) Plot VTC with and without body effect Design a parallel CMOS Inverter.	2	CO1
3	DELAY CMOS INVERTER	Design a CMOS inverter delay not more than 100ps for any transition assume 5 micron technology VTN=0.9 V and VTP=1.1 V, VDD=5V,CL=10 PF, Kn=8 micron, MPL per Volt ²	2	CO2
4	TWO I/P CMOS NAND INVERTER	Design a two i/p CMOS NAND inverter plots it's VTC and verified its truth table	2	CO2
5	TWO I/P CMOS NOR INVERTER	Design a two i/p CMOS NOR inverter plots its VTC and verified its truth table.	2	CO3
6	CURRENT MIRROR	Design a current mirror using 5 micron technology to supply 5micron amp load current KP=12Micron,Kn=30micron,VTP=-1.1,VTN=0.9, lambda 0.05 gamma 0.4 v. Plot o/p current and maximum load resistant	2	CO3
7	POWER CONSUMPTION CMOS	Determine the power consumption by CMOS inverter completing one switching operation with help of power VDD=5V, CL=1pf, CY=100pf RY=100K determine the effect of lamda on power study the power reported by SPICE in o/p file.	2	CO4
8	CMOS SCHMITT TRIGGER	Design a CMOS Schmitt trigger circuit with two different threshold voltage for increasing and decreasing input signal. Plot the simulated VTC for CMOS Schmitt trigger also determine threshold voltage for low to high and high to low switching event in noisy environment for the following parameters VTN=1V, VTP=-1V, VDD=5V, KP=2.5e ⁻⁵	2	CO5
e-Lear	ning Source:			

		Course Articulation Matrix: (Mapping of COs with POs and PSOs)													
PO- PSO CO	PO1	PO2	PO3	PO4	PO5	PO6	PO7	PO8	PO9	PO10	PO11	PO12	PSO1	PSO2	PSO3
CO1	3	3	2	3	2	3		1	3	2		3	3	2	2
CO2	3	2	1		1		1					3	2	1	1
CO3	3	1	1	1	1							3	2	1	
CO4	3	2			1	1						3	2	1	1
CO5	3	1			1							3	2	1	

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